



Attorney's Docket No.: 12732-170001 / US6682

IPW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto Art Unit : 1765
Serial No. : 10/689,617 Examiner : LAN VINH
Filed : October 22, 2003
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING
SEMICONDUCTOR DEVICE

Mail Stop Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO ACTION OF AUGUST 8, 2005

Please amend the above-identified application as follows: